

Amendments to the Specification:

Please replace the paragraph beginning at page 5, line 25 to page 6, line 16, with the following rewritten paragraph:

The method of manufacturing the thin-film magnetic head of the invention comprises the steps of: forming the first pole layer; forming the thin-film coil on the first pole layer; forming the gap layer on the pole portion of the first pole layer; forming a magnetic layer for forming the throat height defining layer on the gap layer; forming a mask on the magnetic layer for making the end portion of the magnetic layer for defining the throat height; forming the end portion of the magnetic layer by selectively etching the magnetic layer through the use of the mask; forming a nonmagnetic layer so as to fill an etched portion of the magnetic layer while the mask is left unremoved; removing the mask after the nonmagnetic layer is formed; forming the track width defining layer on the magnetic layer and the nonmagnetic layer after the mask is removed; and etching the magnetic layer, the gap layer and a portion of the first pole layer to align with the width of the track width defining portion of the track width defining layer, so that the magnetic layer is formed into the throat height defining layer and that each of the portion of the first ~~magnetic-pole~~ layer, the gap layer, the throat height defining layer and the track width defining portion has a width that is taken in the medium facing surface and equal to the track width.